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AF/1765

Docket No.: 8733.154.00-US  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Jin Jang, et al.

Confirmation No.: 7883

Application No.: 09/350,313

Group Art Unit: 1765

Filed: July 9, 1999

Examiner: R. Kunemund

For: METHOD OF CRYSTALLIZING  
AMORPHOUS SILICON LAYER AND  
CRYSTALLIZING APPARATUS THEREOF

Customer No.: 30827

**AMENDMENT AFTER FINAL UNDER 37 C.F.R. SECTION 1.116**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Final Office Action dated December 9, 2003 (Paper No. 20), please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 9 of this paper.